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Automated **defect classification** system
VH Brecher, BL Paul, RW Hall, DM Parisi, R ... - US Patent ..., 1996 - Google Patents
... describe a **wafer defect** detection and classi- fication system in "An Automated **Wafer** Inspection
System ... **based** classifier that does not provide for uncer- tainty in the **defect** measures ... literature
on using concepts of fuzziness as an uncertainty measure in classification applications ...
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Automatic **defect classification** for semiconductor manufacturing
PB Chou, AR Rao, MC Sturzenbecker, FY Wu, ... - Machine Vision and ..., 1997 - Springer
... Patterned **wafer** inspection tools can optically detect **defects** less than 0.5 micron in di- ameter. ...
Much of the excitement of ADC arises from the challenge of the classification technology ... be
constructed by representing their knowledge in terms of **rules** that relate **defect** attributes to ...
Cited by 43 - Related articles - BL Direct - All 3 versions

Model-**based** clustering for integrated circuit yield enhancement
JY Hwang, W Kuo - European Journal of Operational Research, 2007 - Elsevier
... The curvilinear feature is one of the typical patterns observed on **wafer defect** maps with ...
Approximate modeling of curvilinear **defect** patterns with the bivariate normal **distribution** may ...
information about the characteristics of clusters and decrease the classification capability [14]. ...
Cited by 11 - Related articles - All 7 versions

Monitoring **wafer** map data from integrated circuit fabrication processes for spatially clustered **defects**
MH Hansen, VN Nair, DJ Friedman - Technometrics, 1997 - JSTOR
... In general, clusters of **defects** can be **classified** as either particle or process related, with
particle-related clus- ters being assignable to individual machines and process- related clusters
being ... MONITORING **WAFER** MAP DATA FOR SPATIALLY CLUSTERED **DEFECTS** ...
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[PDF] Recent progress in industrial machine vision   mva-org.jp [PDF]
O Montani, JLC Sanz - International Journal of Robotics and Automation, 1993 - mva-org.jp
... patches. The **likelihood** of the presence of the match of a fea- ture point in the other
image should be high. It ... circuited region. To obtain statistical information on the
wafer, a **defect** classification circuit can be used. This circuit ...
Cited by 10 - Related articles - View as HTML - BL Direct - All 4 versions

[PDF] Determining composition of grain mixtures by texture **classification based** on feature **distributions**   psu.edu [PDF]
T Ojala, M Pietikäinen, J Nisula - International Journal of Pattern ..., 1996 - Citeseer
... The proposed applications include, for example, the detection and identification of surface **defects**
on metal surfaces, textiles or semiconductor **wafers**, the assessment of ... This procedure was
repeated for all samples and the classification error rate was determined as the ...
Cited by 13 - Related articles - View as HTML - BL Direct - All 10 versions

A cost-**based** heuristic for statistically determining sampling frequency in a **wafer** fab
CF Chien, SC Hsu, S Peng, CH Wu - 2000 - 140.114.72.26
... However, 100% inspection is practiced at **wafer** sort to **classify** dice, we assume that there is ... as
well as the optimal allocation of inspection capacity depends on the **defect** variability ... needed
for extending the proposed method to deal with the whole in-line **wafer** sampling strategy ...
Cited by 4 - Related articles - View as HTML - All 2 versions

A model-**based** clustering approach to the recognition of the spatial **defect** patterns produced during semiconductor fabrication
T Yuan, W Kuo - IIE Transactions, 2008 - informaworld.com
... The indexing values for classification, the yi in the classification **likelihood** function (2), satisfy
yi = k if zik = 1. In the parameter estimation ... In the simulation studies, the diameter of the **wafers**
is 20 cm. ... The intensity function used in the global **defect** generation is quadratic, that is ...
Cited by 1 - Related articles - BL Direct - All 3 versions

A hybrid fuzzy-statistical clustering approach for estimating the time of changes in fixed and variable sampling control charts
A Alaeddini, M Ghazanfari, MA Nayeri - Information Sciences, 2009 - Elsevier
... and more rational than revised C-charts which are used in monitoring **wafer defects** during IC ...
[4] use expert technology to select unstable slicing machines to control **wafer** slicing quality ... (2)
Similar to clustering methods, change-point models are used to **classify** patterns: almost ...
Cited by 3 - Related articles - All 2 versions

Spatial **defect** pattern recognition on semiconductor **wafers** using model-**based** clustering and Bayesian inference
T Yuan, W Kuo - European Journal of Operational Research, 2008 - Elsevier
... Section 2 describes the mixture model used to describe the **defect distributions** on the **wafers**. ...
In both approaches, the locations s i are regarded as incomplete data and the complete data
are considered to be (s i , z i), where the classification variables z i =(z i0 ,z i1 ,...,z iG),i ...
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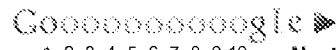
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